



CALIBRATED LEAK STANDARDS FOR GAS FLOW CONTROL

Fast • Accurate • Accredited

Technologies such as OLEDs for TV and smart-phone displays, or other layered materials require the removal of material using an ion source to complete the characterization, and accurate calibration of the flow of argon into the ion source is essential for a reliable and reproducible rate of removal of material. Small changes in layer thickness can have a big impact on device performance; therefore, LACO's leak standards are a critical component for customer confidence in analysis results

They are made for system integration where the application for the system being built only requires one very precise and accurate gas flow rate. Perfect for etching and deposition system OEM's who need better accuracy, lower upfront cost, and lower maintenance cost. They can replace variable leak valves or MFC's. LACO leak standards are the best choice for flow rates from 1×10^{-2} down to 3×10^{-9} atmcc/sec and that have a specific flow rate set for their process.

